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FIG. 1A

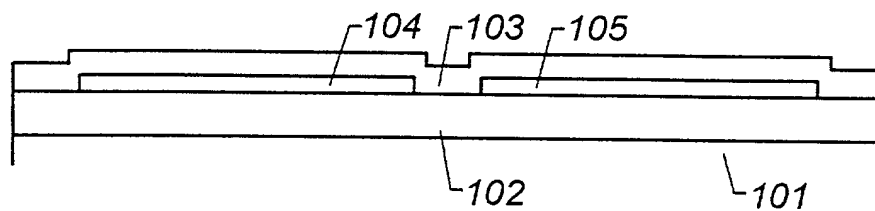


FIG. 1B

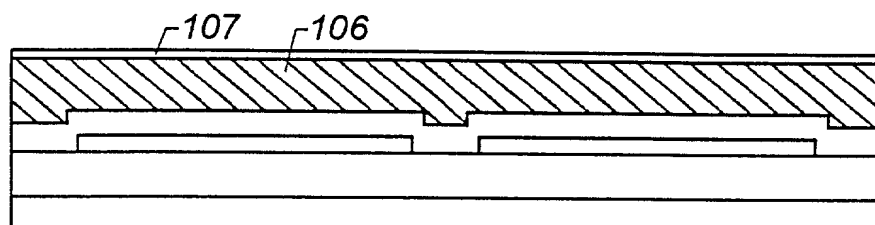


FIG. 1C

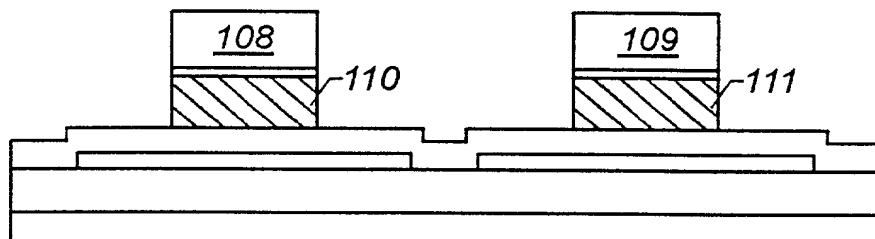


FIG. 1D

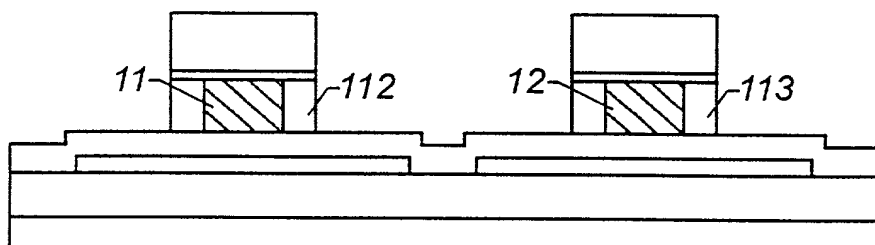


FIG. 1E

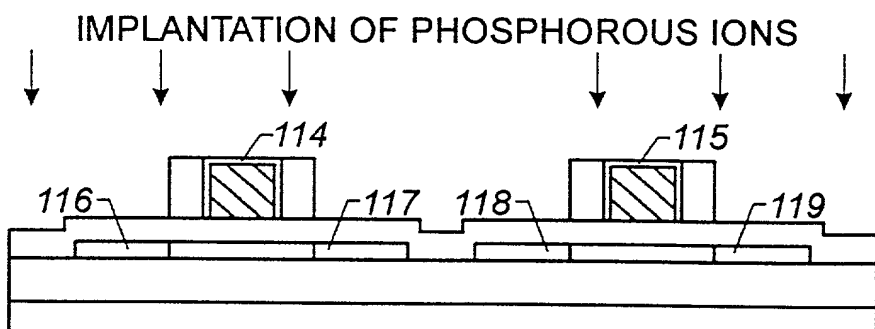


FIG. 2A

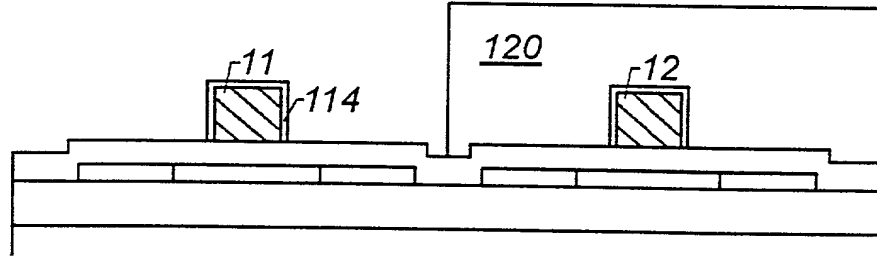


FIG. 2B

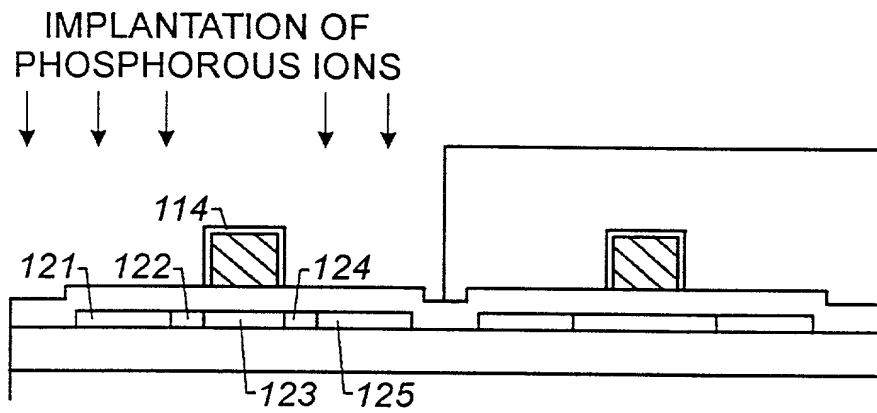


FIG. 2C

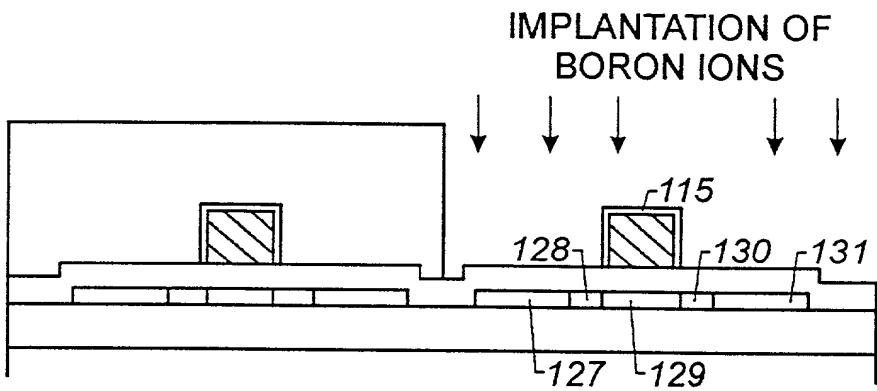


FIG. 2D

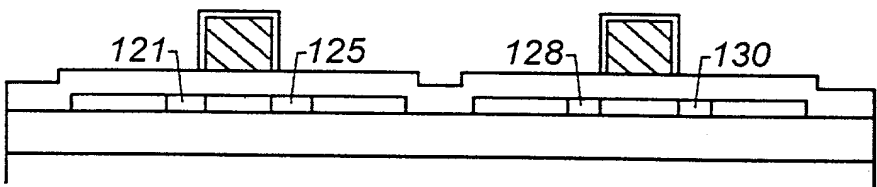


FIG. 3A

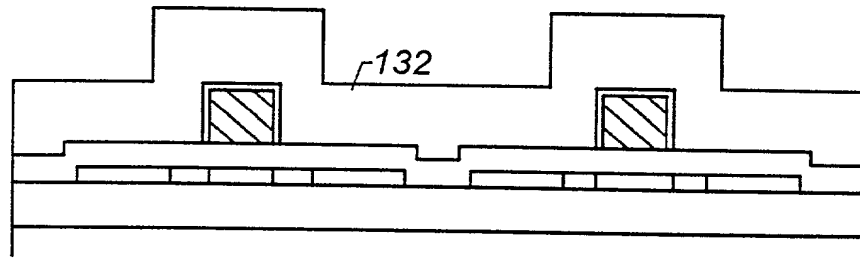
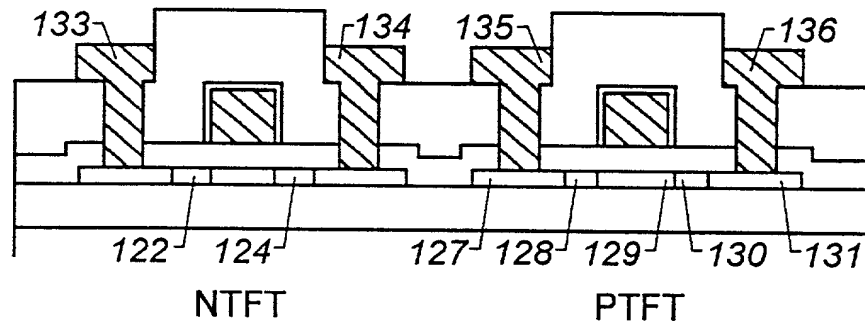


FIG. 3B



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FIG. 4A  
(PRIOR  
ART)

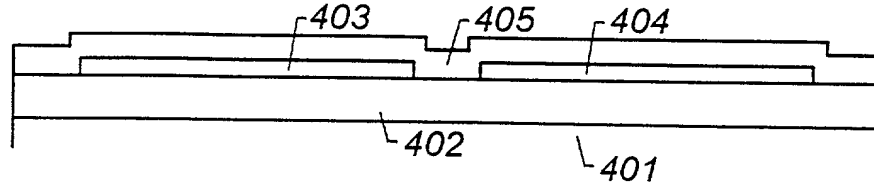


FIG. 4B  
(PRIOR  
ART)

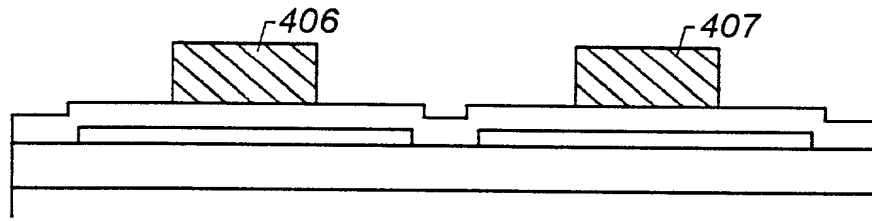


FIG. 4C  
(PRIOR  
ART)

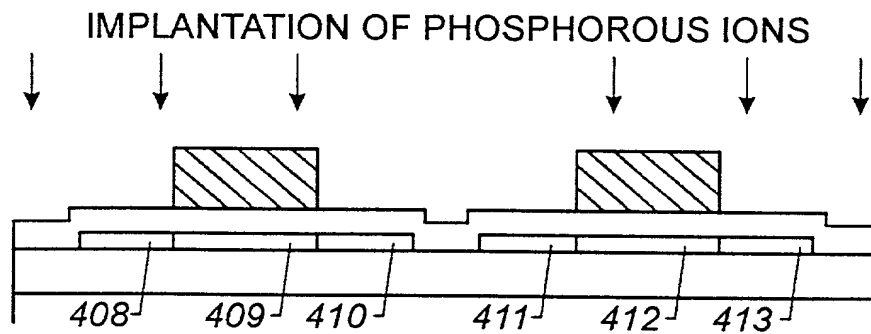


FIG. 4D  
(PRIOR  
ART)

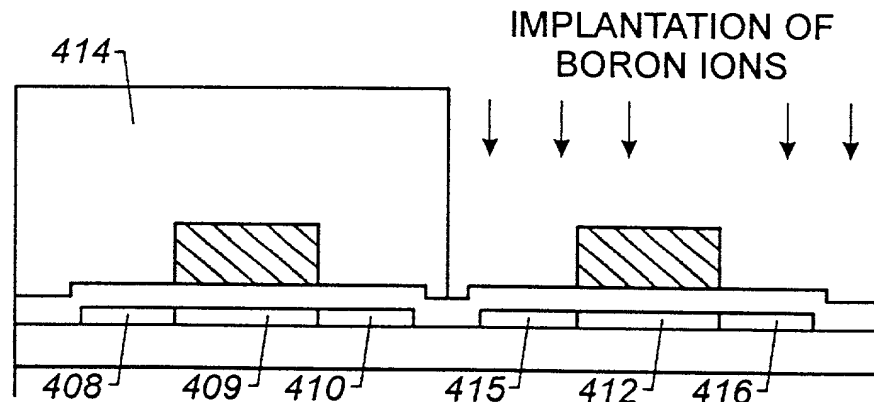


FIG. 5A

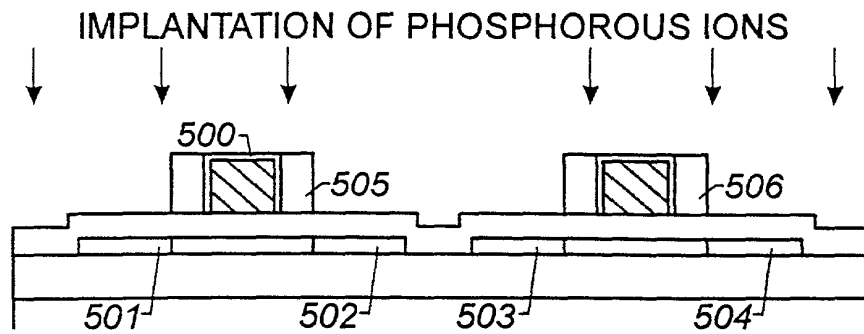


FIG. 5B

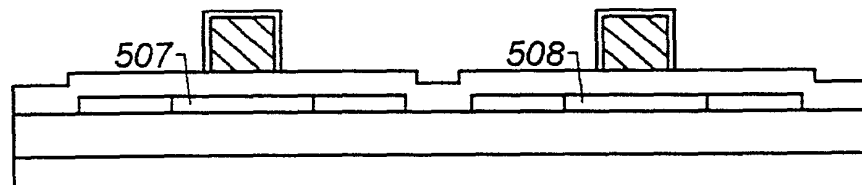


FIG. 5C

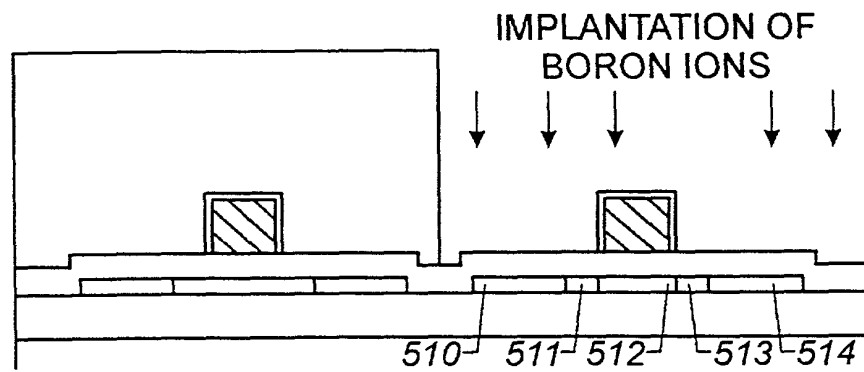
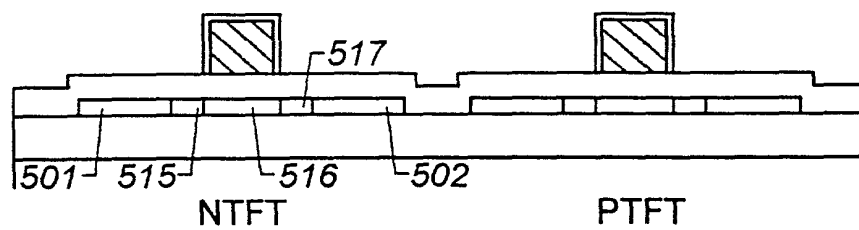


FIG. 5D



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FIG. 6A

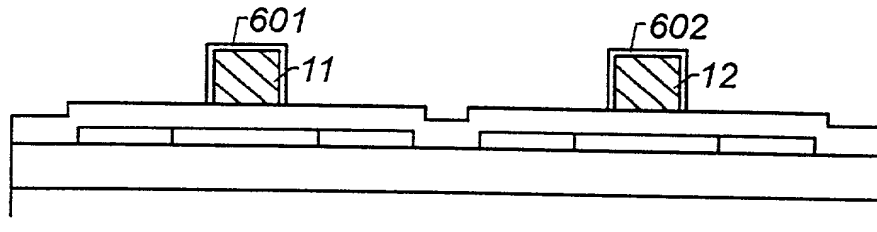


FIG. 6B

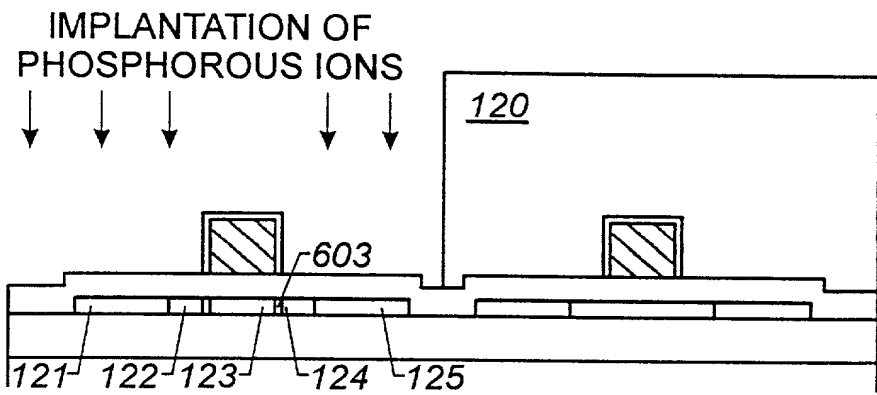


FIG. 6C

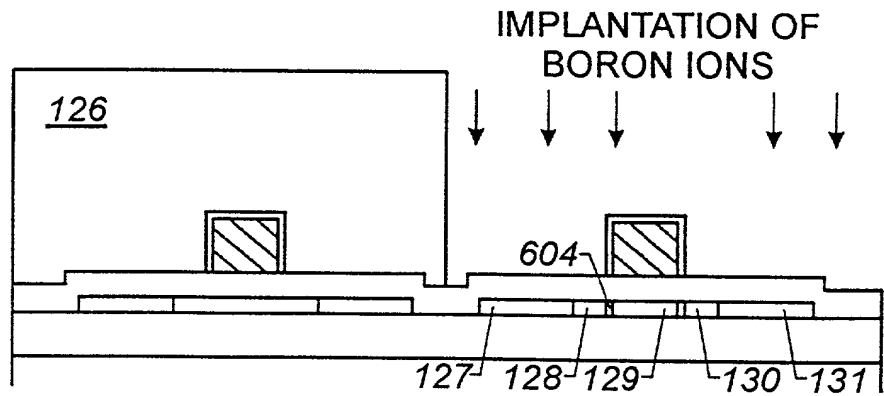
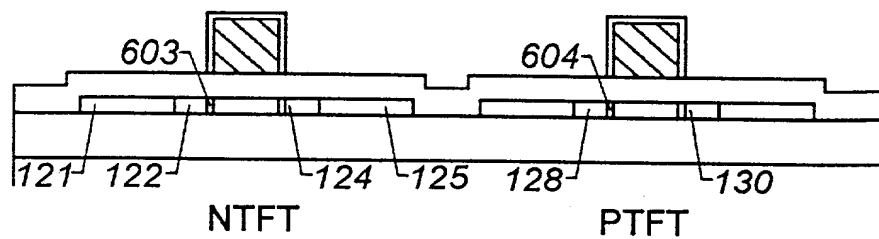


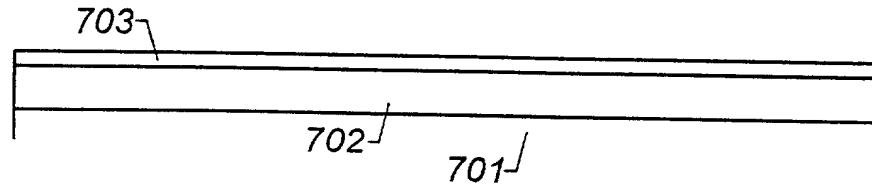
FIG. 6D



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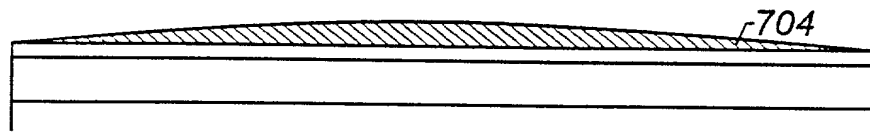
# FORMATION OF AMORPHOUS SILICON FILM

FIG. 7A



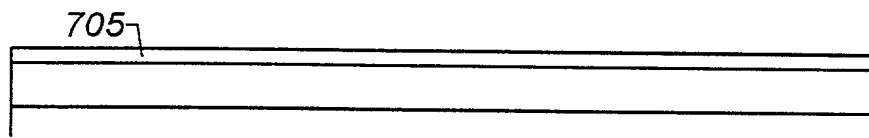
## FORMATION OF WATER FILM CONTAINING NICKEL SALT

FIG. 7B



## HEATING PROCESS FOR CRYSTALIZATION

FIG. 7C



## HEATING PROCESS IN ATMOSPHERE CONTAINING HALOGEN ELEMENT

FIG. 7D

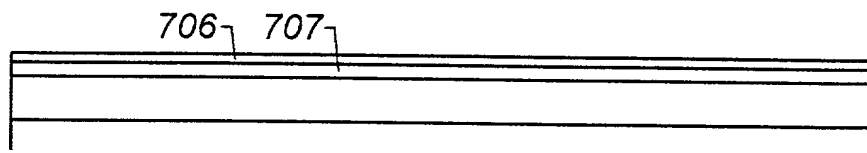


FIG. 7E

